

ABSTRACT

PLASMA CVD APPARATUS, MAGNETIC RECORDING MEDIUM AND METHOD
FOR MANUFACTURING THE SAME

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To provide a plasma CVD apparatus capable of suppressing the generation of discharge at the back face of an anode. The plasma CVD apparatus of the present invention includes a chamber, a plasma wall 8 that is disposed in the chamber and has opened both ends, a holding part that holds a substrate to be deposited 1 disposed near the opening of one end of the plasma wall, an anode disposed so as to cover the opening of the other end of the plasma wall, a filament-shaped cathode disposed on an inner side of the anode and near the opening of the other end of the plasma wall, an AC power supply that is electrically connected to one end of the cathode via a first wiring and is electrically connected to the other end of the cathode via a second wiring, and a hole which is provided at the anode, and through which each of the first wiring and the second wiring passes.

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Fig. 1